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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Cho et al.

Atty Docket No.: NOVLP089/NVLS-2886/2887

Application No.: 10/800,377

Examiner: Picardat, Kevin M.

Filed: March 11, 2004

Group: 2822

Title: METHOD AND APPARATUS FOR UV
EXPOSURE OF LOW DIELECTRIC CONSTANT
MATERIALS FOR POROGEN REMOVAL AND
IMPROVED MECHANICAL PROPERTIES

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as first-class mail on June 29, 2006 in an envelope addressed to the Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450

Signed: _____

Tara Hayden

**INFORMATION DISCLOSURE STATEMENT
BEFORE FINAL ACTION OR NOTICE OF ALLOWANCE
(37 CFR §§ 1.56 AND 1.97(c))**

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

The references listed in the attached PTO Form 1449, a copy of which is attached, may be material to examination of the above-identified patent application. Applicants submit this reference in compliance with their duty of disclosure pursuant to 37 CFR §§1.56 and 1.97. The Examiner is requested to make this citation of official record in this application.

This Information Disclosure Statement is not to be construed as a representation that a search has been made, that additional information material to the examination of this application does not exist, or that this reference indeed constitutes prior art.

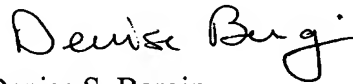
This Information Disclosure Statement is being filed after the mailing date of the first Office Action on the merits, or after three months of the filing date of this application, whichever event occurred last, but it is believed before the mailing date of either: (i) a final action under §1.113 or (ii) a notice of allowance under §1.311, whichever occurs first.

Accompanying this Information Disclosure Statement is

- ☐ a statement as specified in 37 CFR 1.97(e); or
- ☒ the fee set forth in 37 CFR 1.17(p).

If fees are due, enclosed is our Check No. 12121 for \$180.00 in payment of the Information Disclosure Statement Fee. If it is determined that any additional fees are due, the Commissioner is hereby authorized to charge such fees to Deposit Account 500388 (Order No. NOVLP089).

Respectfully submitted,
BEYER WEAVER & THOMAS, LLP



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Form 1449 (Modified) Information Disclosure Statement By Applicant (Use Several Sheets if Necessary)	Atty Docket No.	Application No.:
	NOVLP089/ NVLS-2887	10/800,377
	Applicant:	
	Cho et al.	
	Filing Date	Group
	March 11, 2004	2822

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
	A1	6,573,030 B1	06.03.03	Fairbairn et al.			
	A2	2004/0096586 A1	05.2004	Schulberg et al.			
	A3	2003/0198895 A1	10.2003	Toma et al.			
	A4	6,846,380 B2	01.2005	Dickinson et al.			
	A5	6,867,086 B1	03.2005	Chen et al.			
	A6	6,903,004	06.2005	Spencer et al.			
	A7	6,232,658 B1	05.2001	Catabay et al.			
	A8	6,171,661	01.2001	Zheng et al.			
	A9	2002/0016085	02.2002	Huang et al.			
	A10	6,455,417	09.2002	Bao et al.			
	A11	7,018,918	03.2006	Kloster et al.			
	A12	6,849,549	02.2005	Chiou et al.			

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	C1	Subramonium et al., "Pulsed PECVD Method for Modulating Hydrogen Content in Hard Mask", U.S. Application No. 11/318,269, filed December 23, 2005 (Atty Dkt: NOVLP144/NVLS-3102)
	C2	U.S. Office Action mailed February 28, 2006, from U.S Application No. 10/404,693 [Atty Dkt No. NOVLP064/NVLS-794].
	C3	U.S. Office Action mailed May 31, 2006, from U.S Application No. 10/941,502 [Atty Dkt No. NOVLP107/NVLS-2932].
	C4	U.S. Office Action mailed May 30, 2006, from U.S Application No. 10/785,235 [Atty Dkt No. NOVLP085/NVLS-2875].
	C5	U.S. Office Action mailed May 31, 2006, from U.S Application No. 10/849,568 [Atty Dkt No. NOVLP083/NVLS-2867].
	C6	U.S. Office Action mailed May 2, 2006, from U.S Application No. 11/050,621 [Atty Dkt No. NOVLP100/NVLS-2956].
	C7	U.S. Office Action mailed June 15, 2006, from U.S Application No. 10/800,409 [Atty Dkt No. NOVLP098/NVLS-2907].
	C8	Kelman et al., "Method for Reducing Stress in Porous Dielectric Films", U.S. Application No. 11/369,311, filed March 6, 2006 (Atty Dkt: NOVLP154/NVLS-3121)
	C9	U.S. Office Action mailed May 2, 2006, from U.S Application No. 10/295,965.
	C10	U.S. Office Action mailed August 9, 2005, from U.S Application No. 10/295,965.
Examiner		Date Considered

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.